ON Semiconductor



Issue Date: 27 April 2015

Title of Change:	LSI FLIP fab site change from Gunma, Japan to Niigata, Japan						
Proposed first ship date:	12 September 2016						
Contact information:	Contact your local ON Semiconductor Sales Office or <u>Akira.Yoneyama@onsemi.com</u>						
Samples:	Samples should be available after completion of qualification. Contact your local ON Semiconductor Sales Office or <u>Makoto.Nakaoka@onsemi.com</u>						
Type of notification:	This is an Initial Product/Process Change Notification (IPCN) sent to customers. IPCNs are issued at least 120 days prior to implementation of the change. An IPCN is advance notification about an upcoming change and contains general information regarding the change details and devices affected. It also contains the preliminary reliability qualification plan. The completed qualification and characterization data will be included in the Final Product/Process Change Notification (FPCN). This IPCN notification will be followed by a Final Product/Process Change Notification (FPCN) at least 90 days prior to implementation of the change. In case of questions, contact <pcn.support@onsemi.com>.</pcn.support@onsemi.com>						
Change Part Identification:	dentification: Product lots will be identified through a date code marked on the parts						
Change category(s): Uafer Fab Change Assembly Change Test Change	Manufacturing Site Change/Addition Manufacturing Process Change Material Change	 Product specific change Datasheet/Product Doc change Shipping/Packaging/Marking Other: 					
Sites Affected: All site(s) not applicable ON Semiconductor site(s) : External Foundry/Subcon site		<u>Site 2</u>					
Description and Purpose:	· ·						

To be able to continuously supply products and increase our supply capacity to support increased demand, LSI FLIP site will be changed from Gunma, Japan to Niigata, Japan. All equipment and most personnel will be transferred from the Gunma to the Niigata site. The Niigata site is ISO/TS16949 certified. Neither change in electrical characteristics, nor change in product reliably is expected

ON Semiconductor



C Relia	ability Plan						
0 RE	FERENCE D	DCUMENTS: 12MSB17722C -	Product Reliability Qualificatio	n Process Specific	ation		
	LP/FLIP Reli b site chang	ability Plan e from Gunma, Japan to Niig	ata, Japan				
	WLCSP179 Package WLCSP36 WLFCP6		Wafer Fab Site	Niigata			
0 RE		ESTING REQUIREMENTS					
	Test	Test Conditions	End Point Requirements	Sample Size	# of Lots	Total Units	Comments
	HTOL	TJ ~ 150°C, for 1008 hrs	Test @ Room	77	3	231	
	HTSL	150°C for 1008 hrs	Test @ Room	77	3	231	
	тнв тс	85°C/85% RH for 1008 hrs -40°C to +125°C for 500 cycles	Test @ Room Test @ Room	77 77	3	231 231	
st of		be available after completion	of Qualification.				